



Micro/Nano Photonic Devices and Systems

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Message from the Guest Editors

Dear Colleagues,

This Special Issue seeks reviews, regular research papers, and short communications on the advances in the science and technologies that enable the miniaturization of photonic devices and systems. Areas of interest include, but are not limited to, novel fabrication techniques, materials synthesis, optical properties of nano and micro structures and materials, novel device structures or concepts, new insights into device/system design, modeling, and characterization, device/system actuation and tuning, packaging and integration, and the innovative use of miniaturized photonic devices and systems in applications including, but are not limited to, sensing, display and imaging, energy conversion, optofluidics, data storage, communication, microscopy, spectroscopy, optical MEMS, and quantum information processing.

Prof. Dr. Pei-Cheng Ku

Prof. Dr. Jaeyoun (Jay) Kim

Guest Editors





Editor-in-Chief

Message from the Editor-in-Chief

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